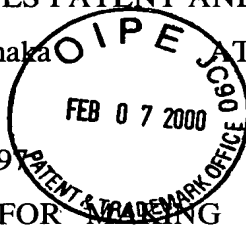


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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

APPLICANT: Hiroshi Tayanaka
SERIAL NO. 08/818,239
FILING DATE: March 14, 1997
INVENTION: "METHOD FOR MAKING THIN FILM SEMICONDUCTOR, SOLAR CELL, AND LIGHT EMITTING DIODE"

ATTORNEY DOCKET NO. P97,0027
GROUP ART UNIT: 2813
EXAMINER: K. Christiansen



SUBMISSION OF SUPPLEMENTAL DECLARATION AND
POWER OF ATTORNEY AND COPY OF ENGLISH TRANSLATION
OF JAPANESE PRIORITY DOCUMENT

RECEIVED

Asst. Commissioner of Patents
Washington, D.C. 20231

FEB 15 2000
TECHNOLOGY CENTER 2800

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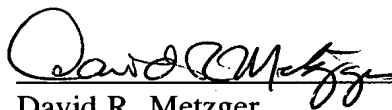
Applicant submits herewith a supplemental Declaration and Power of Attorney fully executed by the inventor of record in the above-identified patent application. The attached Declaration and Power of Attorney correctly claims priority to parent Japanese priority application No. P07-037655 as well as Japanese applications Nos. P08-061552 filed March 18, 1996 and P08-234480 filed September 4, 1996.

Also enclosed is an English translation of the Japanese priority document P07-037655.

A check in the amount of \$130.00 to cover the required fee for submitting the enclosed Declaration is enclosed. However, the Commissioner is hereby authorized to charge any additional fees which may be required, or to credit any overpayment to account No. 08-2290. A duplicate of this sheet is enclosed

Respectfully submitted,

OK to Enter

, Reg. 32,919
David R. Metzger
HILL, STEADMAN & SIMPSON, P.C.
A Professional Corporation
85th Floor - Sears Tower
Chicago, Illinois 60606
Telephone: 312/876-0200

Attorneys for Applicant

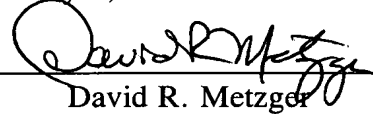
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CERTIFICATE OF MAILING

I hereby certify that this Submission is being deposited with the United States Postal Service as First Class mail in an envelope addressed to: Hon. Commissioner of Patents and Trademarks, Washington, D.C. 20231 on February 4, 2000.

A handwritten signature in dark ink, appearing to read "David R. Metzger", is written over a horizontal line.

David R. Metzger

February 4, 2000